



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Tadahiro OHMI et al.  
Title: VACUUM PROCESSING APPARATUS AND VAPOR  
DEPOSITION APPARATUS  
Appl. No.: 10/568,706  
International 8/19/2004  
Filing Date:  
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Examiner: Keath T. Chen  
Art Unit: 1792  
Confirmation 4847  
Number:

**AMENDMENT AND REPLY UNDER 37 CFR 1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Final Office Action dated September 29, 2009, concerning the above-referenced patent application.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this document.

**Remarks/Arguments** begin on page 4 of this document.

Please amend the application as follows: